

Deterministically Assigned Directional Sensing of Nanoscale Crack based Pressure Sensor by Anisotropic Poisson Ratios of the Substrate

Byeonghak Park, † *Yunheum Lee,* ‡ *Woojin Jung,* † *Dylan K. Scott,* § *Daniel Aalto,* §, ⊥ *Hyun-Joong Chung,* # *and Tae-il Kim* *, †, ‡

† School of Chemical Engineering, Sungkyunkwan University (SKKU), Suwon 16419, Republic of Korea

‡ Department of Biomedical Engineering, Sungkyunkwan University (SKKU), Suwon, 16419, Republic of Korea

§ Department of Communication Sciences and Disorders, Faculty of Rehabilitation Medicine, University of Alberta, Edmonton, T6G 2G4, Canada

⊥ Institute for Reconstructive Sciences in Medicine, Misericordia Community Hospital, Edmonton, Alberta, T5R 4H5, Canada

Department of Chemical and Materials Engineering, Faculty of Engineering, University of Alberta, Edmonton T6G 1H9, Canada

Corresponding author: taeilkim@skku.edu

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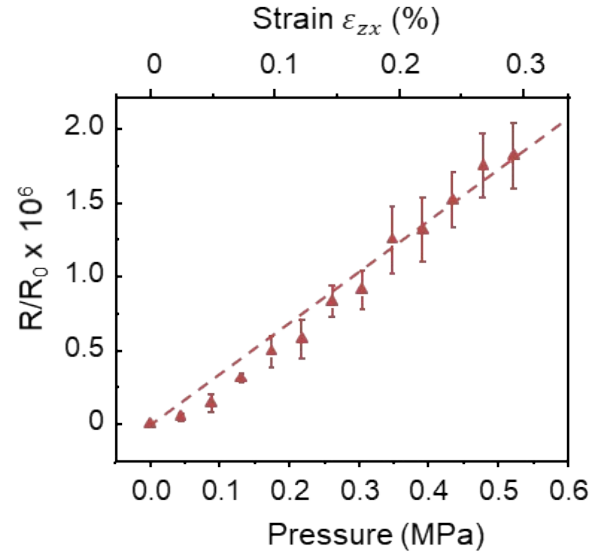


Figure S1. Linear resistance profile under 0.6 MPa pressure.

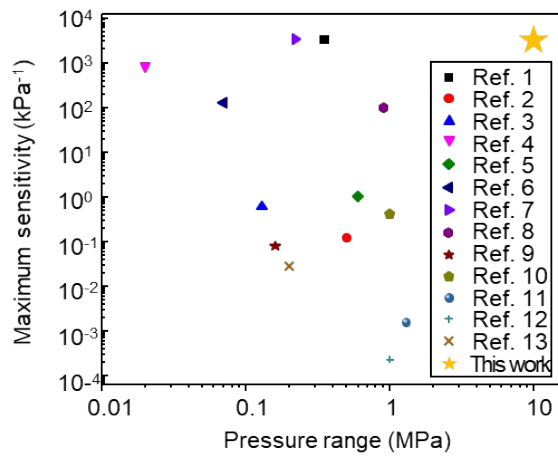


Figure S2. Comparison of pressure ranges and maximum sensitivity.

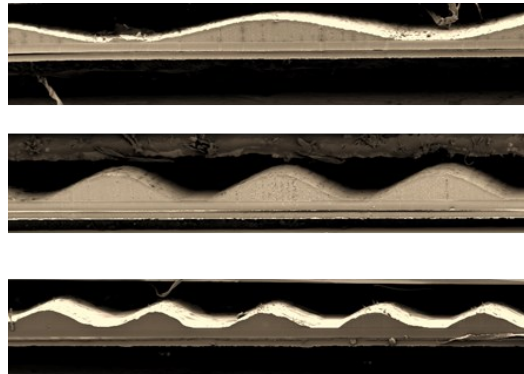


Figure S3. 3D printed half-honeycomb groove molds with different angles, 15°, 30°, and 45°. (Scale bar: 600 μm)

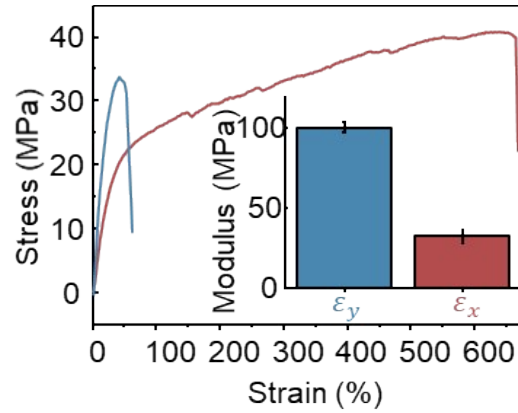


Figure S4. Stress-strain curves of each x and y directional deformation.

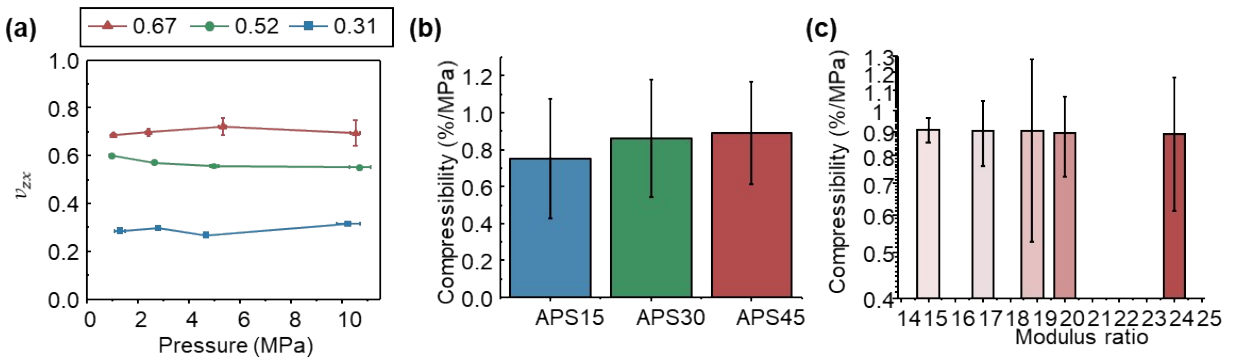


Figure S5. (a) Consistency of Poisson's ratio under various pressures at each controlled APS. (b) Compressibility (z-Strain/Pressure) of APS with APS15, 30 and 45. (c) Compressibility of APS with different modulus ratio.

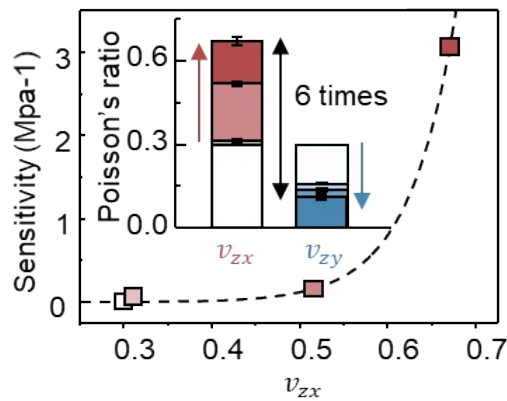


Figure S6. The sensitivity and anisotropy changes under Poisson's ratio

Table S1. Modulating the moduli by mixing two different PUA.

	Soft PUA	Hard PUA	6:1	7:1	8:1	9:1	10:1
Modulus (MPa)	5.1	820.8	120.6	105.1	90.7	79.3	75.2

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